

WORKSHOP

“INDUSTRIAL APPLICATIONS OF SILICON CARBIDE”

THURSDAY 18TH OF NOVEMBER:

7:45	Shuttle bus from the Hotels located at “Porte du Valvert” (Lyon-Tassin)	
8:30 – 9:00	Registration	
9:00 – 10:40	<i>Welcome and Introduction</i>	G. Ferro
9:45 – 10:45	<i>SiC as a thermo-structural material</i>	S. Jacques
10:45 – 11:15 Coffee Break		
11:15 – 12:15	<i>3C-SiC Devices for Electronic Applications</i>	A. Schöner
12:15 – 14:00 Lunch		
14:00 – 15:00	<i>Brazing of SiC based materials</i>	V. Chaumat
15:00 – 16:00	<i>Aspects and prospects of SiC power devices at SiCED</i>	P. Friedrich
16:00 - 16:30 Coffee Break		
16:30 – 17:30	<i>Overview of SiC markets and players</i>	P. Roussel

Free time in Lyon

20:00 - 23:00	Dinner at the “ Commanderie des Antonins ” 30 Quai Saint Antoine - 69002 Lyon – Tel (0)4 78 37 19 21
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FRIDAY 19TH OF NOVEMBER:

8:15	Shuttle bus from the Hotels located at “Porte du Valvert”	
9:00 – 10:00	<i>SiC technology for power device in STMicroelectronics</i>	M.G. Saggio
10:05 – 11:05	<i>SiC polishing and epitaxy – from R&D to industrial solutions</i>	M. Zielinski
11:05 – 11h30 Coffee Break		
11:30 – 12:30	<i>‘Crystal Innov’: presentation of the Crystal Growth Center</i>	P. Jeandel
12:30 – 14:00 Lunch		
14:30	End of the workshop	